

ELECTRICAL CONTACT DEVICE AND ITS MANUFACTURING PROCESS

ABSTRACT

A method of making an electrical contact device includes the step of (a) preparing a substrate, (b) forming a dielectric layer on a surface of the substrate and forming a well on the dielectric layer by means of a non-etching technique, (c) forming a first sacrifice layer in the well, (d) forming a second sacrifice layer on the dielectric layer and the first sacrifice layer and defining a probe body contour and forming a probe body metal layer in the probe body contour and then repeating this step once or several times to form a probe structure, and (e) removing the sacrifice layers to obtain the desired electrical contact device having the substrate and the probe structure.

Figure 1